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CONFIRMATION NO. 1576

SERIAL NUMBER	FILING or 371(c) DATE	CLASS	GROUP ART UNIT	ATTORNEY DOCKET NO.
10/553,573	10/17/2005	427	1715	Serie 6070
RULE				
APPLICANTS Christian Dussarrat, Ibaraki, JAPAN; Jean-Marc Girard, Paris, FRANCE; Takako Kimura, Tsukuba, JAPAN; Naoki Tamaoki, Tokyo, JAPAN; Yuusuke Sato, Tokyo, JAPAN;				
** CONTINUING DATA ***** This application is a 371 of PCT/IB04/01346 04/08/2004				
** FOREIGN APPLICATIONS *****				
** IF REQUIRED, FOREIGN FILING LICENSE GRANTED ** 05/30/2006				
Foreign Priority claimed <input checked="" type="checkbox"/> Yes <input type="checkbox"/> No 35 USC 119(a-d) conditions met <input checked="" type="checkbox"/> Yes <input type="checkbox"/> No Verified and /ELIZABETH A Acknowledged BURKHART/ Examiner's Signature	<input type="checkbox"/> Met after Allowance Initials	STATE OR COUNTRY JAPAN	SHEETS DRAWINGS 5	TOTAL CLAIMS 18
INDEPENDENT CLAIMS 3				
ADDRESS American Air Liquide, Inc. Intellectual Property Dept. 2700 Post Oak Boulevard Suite 1800 Houston, TX 77056 UNITED STATES				
TITLE Methods for producing silicon nitride films by vapor-phase growth				
FILING FEE RECEIVED 1000	FEES: Authority has been given in Paper No. _____ to charge/credit DEPOSIT ACCOUNT No. _____ for following:		<input type="checkbox"/> All Fees <input type="checkbox"/> 1.16 Fees (Filing) <input type="checkbox"/> 1.17 Fees (Processing Ext. of time) <input type="checkbox"/> 1.18 Fees (Issue) <input type="checkbox"/> Other _____ <input type="checkbox"/> Credit	